

SW Test Workshop Semiconductor Wafer Test Workshop

Analysis for Pre-Mature Worn-out of Vertical Probe Needle



Wiljelm Carl K. Olalia Process Engineer II Probe and Die Sales Department ON Semiconductor Philippines June 5-8, 2016



As shown in the graph below, yield started to go below 95% after the13th wafer.

- Yield becomes more inconsistent on wafer #24 to #59.
 - Yield improve on the 60th wafer after z-cleaning perform using Gel Type Cleaner

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Pad #	Pin	Configuration/Function	Before Z-Cleaning After Z-cleaning					Before Z-Cleaning		After Z-cleaning			
			Photo	Diameter	Photo	Diameter	Pad #	Pin	Configuration/Function	Photo	Diameter	Photo	Diameter
Bondpad1	1	FB		0.743		0.972	bondpad6	6	GND		0.813		0.871
bondpad2	2	ст		0.807		1	Bondpad7	7	GND		0.82		0.826
Bondpad3	3	Control		0.926		1.156	Bondpad8	8	DRV		0.792		0.982
Bondpad4	4	CS		0.964		1.137	Pondpad9	12		alen.	0.844	arite a	1
Trimpad1	n/a	n/a		0.908		1.055	Бонарааз	15			0.044		1
Trimpad2	n/a	n/a		0.816		1.037	Bondpad10	14	VCC		0.771		0.963
Trimpad3	n/a	n/a		0.835		1.156	Trimpad5	n/a	n/a		0.725		0.908
Trimpad4	n/a	n/a	Č)	0.813		0.991	Trimpad6	n/a	n/a		0.817	· ·	0.936
Bondpad5	5	ZCD		0.771		0.991	Trimpad7	n/a	n/a		0.733		0.945

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- Vertical needle verified to have a performance deterioration which is evident on the wafer yields.
- This deterioration is caused by needle tip deformation and debris accumulated on the needle tip which is not been removed by brush alone.
- Brush can only remove the cloudlike dirt but cannot re-shape and remove the debris on needle tip
 - Yield deterioration is due to poor probe tip condition.

 \triangleright



Used Probe Needle

New Probe Needle

~5011m

'<mark>50</mark>x

Needle Life Trend 1200000 1000000 800000 600000 400000 200000 0 Feb Dec'10 Jan Mar Jun Jul Aug Oct Nov Dec Apr May Sep AB85-1AVEF BE13-1AVEI HE13-2AVEI AP69-1BVE AB85-2AVEF AP69-2AVEI BD89 AP69-3BVEF BE16G-3AVEI BE16G-1BVEI BE16G-1BVEI(Extra head)) — BE16-1VE BE16-1VE(1) BE16G-2BVEI -BE16G-4AVEF BE16G-4AVEF(1) BE16G-4AVEF(2) BE16G-4AVEF(3) -Target Life

Maximum needle life recorded so far for Vertical Needle is ranging from 57,063 to 790,022 TD Count.

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Objective/Goals

> To verify if the 1 million touchdown that OEM committed is achievable

> To determine what causes the Pre-Mature Needle Wornout

> To formulate a solution to improve the touchdown count.

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Methodology

- Implement a Touchdown Monitoring System that will count the Touchdown from the Needle Start Life and End Life
- Implement In-Process Monitoring focusing on Yield and Needle Mark Quality.
- Secure the worn-out needle then submit for Material Analysis.

Summary

- Probe Pins were submitted to the Material Analysis and Evaluation Laboratory for Scanning Electron Microscope + Energy Dispersive X-ray (SEM+EDX) Analysis. This is a follow up analysis w/c Pins from Site (1) and Site (2) were reported w/ early wearing problem. Pins from sites (4) and (7) were considered. SEM+EDX will verify any difference between the pins thru morphological and elemental composition analyses.
- The samples were analyzed using SEM+EDX. SEM morphologies showed no wearing problems on pin sites (4) and (7). EDX spectroscopy showed elemental composition of Silver (Ag), Palladium (Pd) and Copper (Cu) on all pins. Pins from Site (7) showed presence Aluminum (Al) w/c may actually coming from the Bonding pads of the die during testing. No Silicon (Si) were detected on Pins from sites (4) and (7) meaning the early wearing problem of pins from sites (1) and (2) were caused by the Silicon.



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SEM+EDX Results





Figure 2. SEM+EDX results on Pin 4

SEM morphologies results on Pin site 4 showed no early wearing problem. EDX spectroscopy showed elemental composition of Copper (Cu), Palladium (Pd), Silver (Ag) and Carbon (C).



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SEM+EDX Results



Figure 2. SEM+EDX results on Fresh Pin 7

SEM+EDX results on Pin site 7 also showed no early wearing problem. EDX detected also Copper (Cu), Palladium (Pd), Silver (Ag) and Carbon (C). Traces of Aluminum (Al) were also found w/c may come from the bonding pads.



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Summary

- Probe Pins were submitted to the Material Analysis and Evaluation Laboratory for Scanning Electron Microscope + Energy Dispersive X-ray (SEM+EDX) Analysis. Pins from Site (1) and Site (2) were reported w/ early wearing problem. A fresh pin was also submitted for correlation. SEM+EDX will verify any difference between the pins thru morphological and elemental composition analyses.
- The samples were analyzed using SEM+EDX. EDX spectroscopy showed elemental composition of Silver (Ag), Palladium (Pd) and Copper (Cu) on all pins. Pins from Site (1) and (2) showed presence of Silicon (Si) and Aluminum (Al) w/c may actually coming from the die during testing. Silicon in a form of glass or Silica (SiO2) is a harder material w/c can scratch the metallic pin during probe testing.



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SEM+EDX Results – Fresh Pin



Figure 2. SEM+EDX results on Fresh Pin

SEM+EDX results on Fresh Pin showed elemental composition of Copper (Cu), Palladium (Pd), Silver (Ag) and Carbon.



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SEM+EDX Results – Site (1) Pin



Figure 3. SEM+EDX results on Site 1 Pin

SEM+EDX results showed wear on Site (1) Pin. EDX detected presence of Aluminum (AI) and Silicon (Si) on the contact area of the pin.



EDX

Full scale = 22_cos

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SEM+EDX Results – Site (1) Pin





Full scale - 17 cps

Figure 3. SEM+EDX results on Site 2 Pin

SEM+EDX results also showed wear on Site (1) Pin. Aluminum (Al) and Silicon (Si) are also present Silicon in the form of passivation/glass (SiO2) is a harder material comparing to the metallic pins. The passivation can cause wear on the pins during contact.



EDX

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Fresh Pin

SEM+EDX results on Fresh Pin showed elemental composition of Copper (Cu), Palladium (Pd), Silver (Ag) and Carbon.

No Early Worn-out

SEM+EDX results showed wear on Site (1) Pin. EDX detected presence of Aluminum (AI) and Silicon (Si) on the contact area of the pin.

With Early Worn-out

SEM+EDX results also showed wear on Site (1) Pin. Aluminum (AI) and Silicon (Si) are also present Silicon in the form of passivation/glass (SiO2) is a harder material comparing to the metallic pins. The passivation can cause wear on the pins during contact.

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Follow-on Work Alternative Probing Pattern

Simulation using an Alternative probe pattern/stepping:

- Using an alternative probing pattern that supported by Mapping System
- Probing pattern now stepping on the y-direction but following the contour of the wafer edge







Crescent Pattern 1

Crescent Pattern 2

Column-Block

Smart Sampling